Notice of References Cited Application/Control No. 10/018,426 Examiner David M Brunsman Applicant(s)/Patent Under Reexamination KIM ET AL. Page 1 of 2

U.S. PATENT DOCUMENTS

		Document Number	Date		
*		Country Code-Number-Kind Code	MM-YYYY	Name	Classification
	Α	US-5,767,030	06-1998	Kim et al.	501/136
	В	US-			
	С	US-			
	D	US-			, , , , , , , , , , , , , , , , , , ,
	Е	US-			
	F	US-			
	G	US-			
	Н	US-			
	ı	US-			
	J	US-			
	К	US-			****
	L	US-			
	М	US-			

FOREIGN PATENT DOCUMENTS

						100
*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	. Name	Classification
	N			•		
	0					
	Р					
	Q					
	R					·
	s					
	Т					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	CAPLUS 2003:354765, Kim et al, "Structure and microwave dielectric properties", 2003
	V	CAPLUS 1999:593074, Kim et al, "Microwave dielectric ceramics" 1999
	w	CAPLUS 1999:818005, Kim et al. "Low-temperature sintering and" 1999
	x	CAPLUS 2000:41577, Kim et al., "Low-fired (Zn,Mg)TiO3 microwave dielectrics" 2000

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

Application/Control No. 10/018,426 Applicant(s)/Patent Under Reexamination KIM ET AL. Examiner David M Brunsman Applicant(s)/Patent Under Reexamination KIM ET AL. Page 2 of 2

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	Α	US-			
le:	В	US-			
	С	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	Н	US-			
	ı	US-			
	J	US-			
	К	US-			
	L	US-	·		
	М	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	0					
	Р					
	Q					
	R	1980				
	s					"
	Т					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	CAPLUS 2000:896800, Purvanova et al, "Preparation and some properties of" 1999
	٧	CAPLUS 1998:395995, Kim et al, "Microstructure and microwave dielectric properties" 1998
	w	CAPLUS 1977:537379, Sheinkman et al, "Phase formation sequence during the reaction" 1977
	х	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.